

FIG.1(Prior Art)

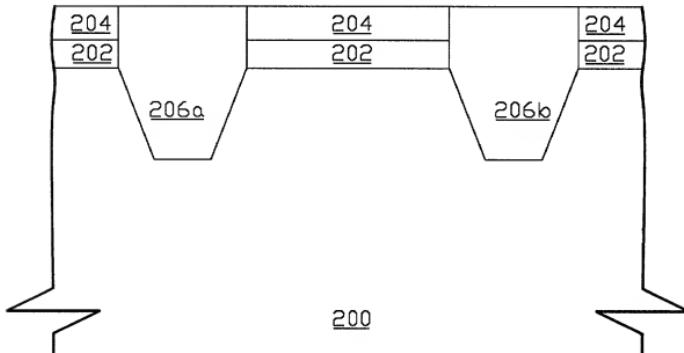


FIG.2A

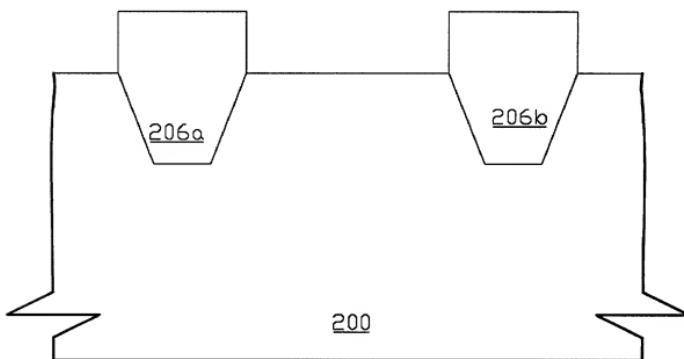


FIG.2B

TITLE: METHOD FOR FORMING SACRIFICIAL OXIDE LAYER
Inventor: Shu-Ya HSU
Docket No. 4425-177

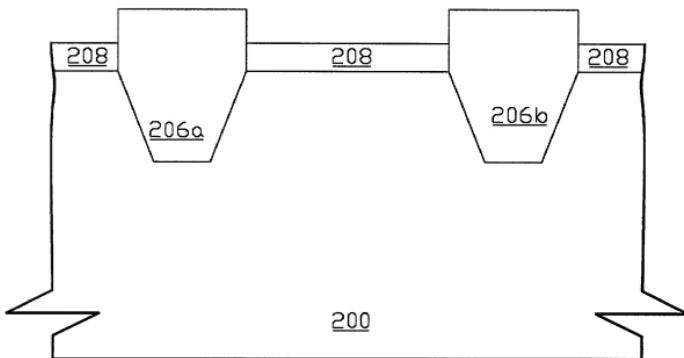


FIG.2C

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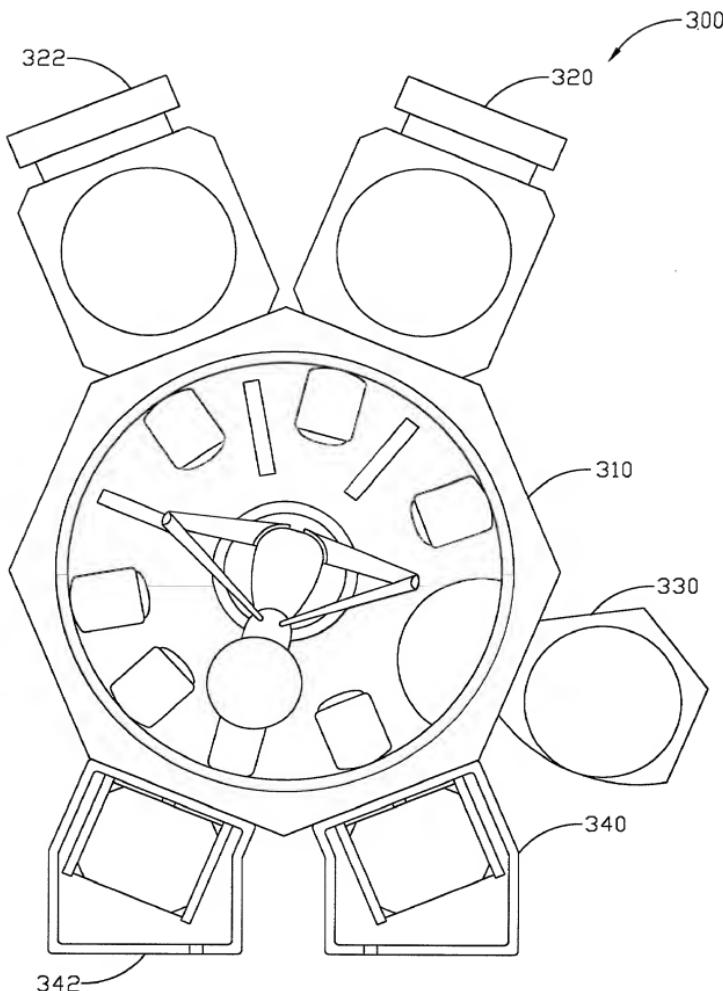


FIG.3